



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Frank Y. Xu et al.

App. No.: 10/789,319 GPAU: 1712

Filing Date: 02/27/2004 Examiner: Marc S. Zimmer

Dkt. No.: P121-63-03 Conf. No.: 9202

For: COMPOSITION FOR AN ETCHING MASK COMPRISING A SILICON-
CONTAINING MATERIAL

INFORMATION DISCLOSURE STATEMENT

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Commissioner for Patents
P.O. Box 1450
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The following information is submitted in compliance with Applicants' duty of disclosure and pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98. The undersigned brings the patents, publications, applications or other information identified in the attached:

Form(s) PTO/SB/08A and/or PTO/SB/08B or PTO/1449
 Other:

to the Examiner's attention in the above-identified application. It is respectfully requested that the cited information be expressly considered during the prosecution of this application, and the references be made of record therein and appear among the "references cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed: before the mailing date of a first Office action on the merits or before the mailing date of a first Office action after the filing of a request for continued examination under § 1.114. Therefore, no fee is believed required.

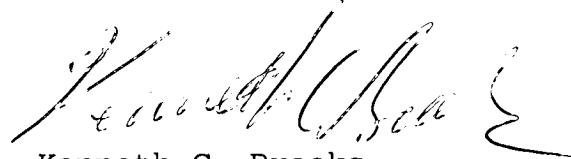
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Signed: Katrina Prati
Typed Name: Katrina Prati
Date: 1/5/09

Respectfully Submitted,



Kenneth C. Brooks,
Reg. No. 38,393
Legal Department
Molecular Imprints, Inc.
P.O. Box 81536
Austin, TX 78758-1536
(512) 339-7760
(512) 491-8918 (fax)



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PTC/SB/03A (03-03)

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Attorney Docket Number	P121-63-03

U.S. PATENT DOCUMENTS

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		Number	Kind Code ² (if known)			
	A1	3,527,062		Belinski et al.	09-08-1970	
	A2	3,783,520		King	01-08-1974	
	A3	3,807,027		Heisler	04-30-1974	
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	A35	4,772,878		Kane	09-20-1988	
	A36	4,808,511		Holmes.	02-28-1989	
	A37	4,826,943		Ito et al.	05-02-1989	
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	A69	5,155,749		DiMilia et al.	10-13-1992	
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	A102	5,417,802		Obeng	05-23-1995	
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	A103	5,421,981		Leader et al.	06-06-1995	
	A104	5,422,295		CHOI et al.	06-06-1995	
	A105	5,424,549		Feldman	06-13-1995	
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	A137	5,747,102		Smith et al.	05-05-1998	
	A138	5,753,014		Van Rijn	05-19-1998	
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Complete if Known

Application Number	10/789,319
Filing Date	02/27/2004
First Named Inventor	Xu et al.
Group Art Unit	1712
Examiner Name	Zimmer, Marc S.
Attorney Docket Number	P121-63-03

U.S. PATENT DOCUMENTS

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Application Number	10/789,319
Filing Date	02/27/2004
First Named Inventor	Xu et al.
Group Art Unit	1712
Examiner Name	Zimmer, Marc S.
Attorney Docket Number	P121-63-03

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		Number	Kind Code ² (if known)			
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Application Number	10/789,319				
Filing Date	02/27/2004				
First Named Inventor	Xu et al.				
Group Art Unit	1712				
Examiner Name	Zimmer, Marc S.				
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INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>				Application Number	10/789,319
				Filing Date	02/27/2004
				First Named Inventor	Xu et al.
				Group Art Unit	1712
				Examiner Name	Zimmer, Marc S.
				Attorney Docket Number	P121-63-03
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		Office ³	Number ⁴	Kind Code ⁵ (if known)				
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				Filing Date	02/27/2004
				First Named Inventor	Xu et al.
				Group Art Unit	1712
				Examiner Name	Zimmer, Marc S.
Sheet	12	of	25	Attorney Docket Number	P121-63-03

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Sheet	13	of	25	Attorney Docket Number	P121-63-03
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Application Number	10/789,319
Filing Date	02/27/2004
First Named Inventor	Xu et al.
Group Art Unit	1712
Examiner Name	Zimmer, Marc S.

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Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
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Examiner Signature	Date Considered
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**INFORMATION DISCLOSURE
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Complete if Known

Application Number	10/789,319
Filing Date	02/27/2004
First Named Inventor	Xu et al.
Group Art Unit	1712
Examiner Name	Zimmer, Marc S.
Attorney Docket Number	P121-63-03

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

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Substitute for form 1449B/PTO				Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>				Application Number	10/789,319
Sheet	17	of	25	Filing Date	02/27/2004
				First Named Inventor	Xu et al.
				Group Art Unit	1712
				Examiner Name	Zimmer, Marc S.
				Attorney Docket Number	P121-63-03

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Examiner Name	Zimmer, Marc S.
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	A433	MARTIN et al., "Predication of Fabrication Distortions in Step and Flash Imprint Lithography Templates.", Journal of Vacuum Science. B 20(6) pp. 2891-2895, November 1, 2002.	
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of

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Application Number	10/789,319
Filing Date	02/27/2004
First Named Inventor	Xu et al.
Group Art Unit	1712
Examiner Name	Zimmer, Marc S.
Attorney Docket Number	P121-63-03

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	A466	SAGIV, "Organized Monolayers by Absorption. 1. Formation and Structure of Oleophobic Mixed Monolayers on Solid Surfaces.", Journal of American Chemical Society/102:1, January 2, 1980.	
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	A472	SRINIVASAN et al., "Alkyltrichlorosilane-Based Self-Assembled Monolayer Films for Stiction Reduction in Silicon Micromachines.", Journal of Microelectromechanical Systems, June 1, 1998, Vol. 7, No. 2, p. 252-260.	
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	A475	SUNG et al., "Abstract of Micro/nano-tribological Characteristics of Self-Assembled Monolayer and its Application in Nano-Structure Fabrication", Elsevier Science B.V., July 1, 2003, Vol. 255, no. 7	
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Sheet	23	of	25	Attorney Docket Number	P121-63-03
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	A485	US Application No. 10/463,396, Filed 06-17-2003, CHOI et al., "Method to Reduce Adhesion Between a Conformable Region and a Pattern of a Mold."	
	A486	US Application No. 10/614,716, Filed 07-07-2003, SREENIVASAN et al., "A Conforming Template for Patterning Liquids Disposed on Substrates."	
	A487	US Application No. 10/666,527, Filed 09-18-03, BAILEY et al., "Imprint Lithography Templates having Alignment Marks."	

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	A498	US Application No. 10/898/037, Filed 07-23-04, MCMACKIN et al., "A System of Creating a Turbulent Flow of Fluid between a Mold and a Substrate."	

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	A501	VANDERBILT, "VU9730 Specifications for Improved Flexure Device.", Vanderbilt University Office of Transfer Technology, 101, 25, 192-199.		
	A502	WANG et al., "Passive Compliance versus Active Compliance in Robot-Based Automated Assembly Systems.", Industrial Robot, January 1, 1998, Vol. 25, No. 1, pp. 48-57.		
	A503	WHITE et al., "Novel Alignment System for Imprint Lithography.", J. Vac. Sci. Technol. B 18(6), November 1, 2000, pp. 3552-3556.		
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	A507	XIA et al., "Soft Lithography.", Annu Rev. Mater. Sci., 1998, 28: 153-184.		

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